

## Configuration check sheet

|    |                         |   |  |
|----|-------------------------|---|--|
| 1  | Check Date              |   | Inspector  |
| 2  | End User                |   |  |
| 3  | Machine Model           | <b>NSR- 4425i</b>   |  |
| 4  | Electric source         | (without/with) NEMA BOX / For (CVCF/UPS) / <b>NEMA Switch</b> (none/1/2)                          |  |
| 5  | Chamber Type            | Maker   | ASAHI / SENDAI   |
|    |                         |   |  |
|    | Production date         | <b>1997. 11</b>   |  |
|    | Model                   | <b>N3A-B</b>  |  |
| 6  | Chamber Size            | Long Body(1950mm) / <b>Short Body(1800mm)</b>   | Chamber EPROM Ver.   |
| 7  | Set Teperature          | <b>Chamber : 23.0</b>   | <b>LLTC:                    </b> °C                        |
|    |                         | <b>IATC(X):                </b> °C  | <b>IATC(Y):                </b> °C                         |
| 8  | Computer Type           | <b>Vax / Alpha Station / DMCC</b>   | Computer Model   |
|    |                         | <b>4000. 96</b>   |  |
| 9  | MCSV Ver.               | <b>2.31D</b>  | OCSV Ver.  |
|    | TOOL Ver.               | <b>2.43B</b>  | BASEKIT Ver.   |
|    |                         | <b>2.31A</b>  |  |
| 10 | ROM Version             | <b>ST - 71 V6.20</b>  | <b>AL - 71 V9.50</b>                                       |
|    |                         | <b>LC - 7M V3.00</b>  | <b>RL - 04 V5.60</b>                                       |
|    |                         | <b>SEN - 10 V1.10</b>   | <b>OF- G3 V2.76</b>  |
|    |                         | PPD   |  |
|    |                         | <b>PA - 71 V5.40</b>  |  |
|    |                         | <b>AWL - 10 V4.80</b>   |  |
|    |                         | INL   |  |
| 11 | HP LASER                | 5517A / <b>5517B</b> / 5517C / 5517D  | LSA LASER  |
|    |                         | <b>5mW / 10mW</b>   |  |
| 12 | Reticle Microscope      | <b>Fixed ( <input type="radio"/> ) / Variable (   mm to   mm ) / setting size ( <b>44mm</b> )</b> |  |
| 13 | Wafer Condition         | Sapphire / <b>Silicon</b> / Other(                    ) )   |  |
| 14 | OF Detection Type       | <b>Nikon Original Type</b> / Omron type / Keyence type <b>Flat</b> / Notch                        |  |
| 15 | Wafer Loader Type       | TYPE1 / <b>TYPE2</b> (A1 / A3 / G3/ B3) / TYPE3   Wafer size : 4, 6, <b>8 inch</b>                |  |
| 16 | Wafer Carrier Table     | <b>Left / Right</b> / Extra   | In-line   no / yes (right / left)                          |
| 17 | Reticle Size            | 5inch(32mm /26mm/18mm) / <b>6inch</b>   | FIA / BCR   no , <b>yes</b> /no , yes                      |
| 18 | Reticle Library Type    | <b>Nikon</b> / Canon  | Slot <b>Main : ( <b>13</b> )slot / Ext. LIB (    )slot</b> |
| 19 | PPD /PD                 | PPD ( <b>no</b> /yes)   | PD( <b>no</b> /yes)  |
| 20 | Rack Type               | Normal ( <b>Right</b> / Left) / Special   Left  |  |
| 21 | SHRINC Type             | <b>None</b> / 1 / 2 / 3   | Illumination Setting   Attachment Setting Value            |
| 22 | Cymer Laser Maker /Type | /   |  |
| 23 | BMU Type                | Under Flow / Over Flow  | BMU Model  |
| 24 | BMU Picture             | Attachment BMU Picture or drawing   |  |
| 25 | Backup Method           | FULL / <b>Only Constants DKA200</b>   | Backup Date  |
|    | NOTE                    |   |  |
|    |                         |   |  |
|    |                         |   |  |